



2874

PATENT

Docket No.: 176/60921 (2-11150-912)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Lukas Novotny and Thomas G. Brown)
Serial No. : 10/068,449)
Cnfrm. No. : 9533)
Filed : February 7, 2002)
For : A SYSTEM AND METHOD FOR HIGH)
RESOLUTION OPTICAL IMAGING, DATA)
STORAGE, LITHOGRAPHY, AND)
INSPECTION)

Examiner:
Pearlene Foster

Art Unit:

2823
TECHNOLOGY CENTER 2800

JUN 26 2003

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SECOND SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §§ 1.97-1.98

Mail Stop:

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Dear Sir:

Pursuant to 37 CFR §§ 1.97-1.98, applicants hereby bring to the attention of the
United States Patent and Trademark Office, the enclosed references listed on the attached
PTO-1449 form.

Respectfully submitted,

Date: June 23, 2003

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I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450, on the date below.	
Date	6/23/03
	<u>Sherri A. Moscato</u> Sherri A. Moscato

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use several sheets if necessary) (PTO-1449 JUN 25 2003)	ATTY. DOCKET NO.		SERIAL NO.
	176/60921 (2-11150-912)		10/068,449
	APPLICANT		
	Lukas Novotny and Thomas G. Brown		
	FILING DATE		GROUP ART UNIT
	February 7, 2002		2874

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPRO- PRIATE
	1	5,881,042	03/09/1999	Knight			
	2	5,936,928	08/10/1999	Jain et al.			
	3	5,963,532	10/05/1999	Hajjar			
	4	6,009,064	12/28/1999	Hajjar			
	5	6,055,222	04/25/2000	Knight			
	6	6,061,322	05/09/2000	Jain et al.			
	7	6,111,840	08/29/2000	Hajjar			
	8	6,243,350	06/05/2001	Knight et al.			
	9	6,324,141	11/27/2001	Takishima et al.			
	10	6,407,884	06/18/2002	Osborne et al.			
	11	6,496,468	12/17/2002	Hajjar et al.			
	12	6,507,540	01/14/2003	Berg et al.			
	13	6,522,617	02/18/2003	Berg et al.			
	14	6,529,465	03/04/2003	Kase et al.			
	15	6,544,716	04/08/2003	Hajjar et al.			
	16	6,545,969	04/08/2003	Berg et al.			

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANS- LATION IF APPRO- PRIATE

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)

		17	Pohl et al., "Optical Stethoscopy: Image Recording With Resolution $\lambda 20$," <u>Appl. Phys. Lett.</u> 44:651-653 (1984)
		18	Lewis et al., "Development of a 500 Å Resolution Light Microscope," <u>Ultramicroscopy</u> 13:227-231 (1984)
EXAMINER			DATE CONSIDERED
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			

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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANS- LATION IF APPRO- PRIATE

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)

		19	Betzig et al., "Near-field Optics: Microscopy, Spectroscopy, and Surface Modification Beyond the Diffraction Limit," <u>Science</u> 257:189-195 (1992)
		20	Smolyaninov et al., "Near-field Direct-write Ultraviolet Lithography and Shear Force Microscopic Studies of the Lithographic Process," <u>Appl. Phys. Lett.</u> 67:3859-3861 (1995)
		21	Davy et al., "Near-field Optics: Snapshot of the Field Emitted by a Nanosource Using a Photosensitive Polymer," <u>Appl. Phys. Lett.</u> 69:3306-3308 (1996)
		22	Massanell et al., "Nanowriting on Ferroelectric Surfaces with a Scanning Near-field Optical Microscope," <u>Opt. Lett.</u> 21:12-14 (1996)
		23	Madsen et al., "Optical Near-field Lithography on Hydrogen-passivated Silicon Surfaces," <u>Appl. Phys. Lett.</u> 69:544-546 (1996)
		24	Herndon et al., "Near-field Scanning Optical Nanolithography Using Amorphous Silicon Photoresists," <u>Appl. Phys. Lett.</u> 74:141-143 (1999)
		25	Novotny et al., "Theory of Nanometric Optical Tweezers," <u>Phys. Rev. Lett.</u> 79:645-648 (1997)
		26	Novotny et al., "Near-field Optical Spectroscopy Based on the Field Enhancement at Laser Illuminated Metal Tips," <u>Optics and Photonics News</u> 10:24 (1999)
		27	Levi, "Progress Made in Near-field Imaging With Light From a Sharp Tip," <u>Physics Today</u> pp. 18-20 (1999)
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